

### IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

ficant:

Frank Y. Xu et al.

App. No.:

10/763,885

GPAU:

1752

Filing Date:

01/23/2004

Examiner:

Amanda C. Walke

Dkt. No.:

P113-55-03

Conf. No.:

6002

For: M

MATERIALS AND METHODS FOR IMPRINT LITHOGRAPHY

## INFORMATION DISCLOSURE STATEMENT

Mail Stop AMENDMENT Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

#### Sir:

The following information is submitted in compliance with Applicants' duty of disclosure and pursuant to 37 C.F.R. § 1.56, § 1.97 and § 1.98. The undersigned brings the patents, publications, applications or other information identified in the attached:

$\boxtimes$	Form(s)	PTO/SB/08A	and/or	PTO/SB/08B	or	PTO/1449
$\mathbf{Z}\mathbf{Z}$	I OI III (B)	I IO/DD/OOM	and, or	110,00,000	$\circ$	110/1442

□ Other:

to the Examiner's attention in the above-identified application. It is respectfully requested that the cited information be expressly considered during the prosecution of this application, and the references be made of record therein and appear among the "references cited" on any patent to issue therefrom.

This Information Disclosure Statement is being filed:

before the mailing date of a first Office action on the merits or before the mailing date of a first Office action after the filing of a request for continued examination under § 1.114. Therefore, no fee is believed required.

Applicant(s) does not believe that any additional fees are due, but if the Commissioner believes additional fees are due,

the Commissioner is hereby authorized to charge any fees which may be required, or credit any overpayment, to Deposit Account Number 502650.

CERTIFICATE OF TRANSMISSION
I hereby certify that this correspondence is being facsimile transmitted to the USPTO or deposited with the United States Postal Service with sufficient postage as either First Class Mail or Express Mail, in an envelope addressed to the Commissioner for Patents.

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Typed Name: Katrina Prati

Date:

Respectfully Submitted,

Kenneth C. Brooks,

Reg. No. 38,393 Legal Department

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Complete if Known					
Application Number	10/763,885				
Filing Date	01/23/2004				
First Named Inventor	Xu et al.				
Group Art Unit	1752				
Examiner Name	Amanda C. Walke				
Attorney Docket Number	P113-55-03				

				U.S. PATENT DOCUMEN	TS	
Examiner Initials*	Cite No.1	U.S. Patent Doc	ument Kind Code <sup>2</sup> (if known)	Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
	B1	3,527,062		Bilinski et al.	09-08-1970	
	B2	3,783,520		King	01-08-1974	
	B3	3,807,027		Heisler	04-30-1974	
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	B5	3,811,665		Seelig	05-21-1974	
	B6	4,062,600		Wyse	12-13-1977	
	B7	4,070,116		Frosch et al.	01-24-1978	
	B8	4,098,001		Watson	07-04-1978	
	B9	4,119,688		Hiraoka	10-10-1978	
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	B11	4,155,169		Drake et al.	05-22-1979	
	B12	4,201,800		Alcorn et al.	05-06-1980	
	B13	4,202,107		Watson	05-13-1980	
	B14	4,267,212		Sakawaki	05-12-1981	
	B15	4,326,805		Feldman et al.	04-27-1982	
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	B19	4,426,247		Toshiakai et al.	01-17-1984	
	B20	4,440,804		Milgram	04-03-1984	
	B21	4,451,507		Beltz et al.	05-29-1994	
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	B23	4,544,572	<del> </del>	Sandvig et al.	10-01-1985	
	B24	4,552,832		Blume et al.	11-12-1985	
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	B34	4,808,511		Holmes	02-28-1989	
Examiner Signature					Date Considered	

<sup>\*</sup>EXAMINER: Initial if reference considered; whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

<sup>&</sup>lt;sup>1</sup>Unique citation designation number. <sup>2</sup>See attached Kinds of U.S. Patent Documents. <sup>3</sup>Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). <sup>4</sup>For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. <sup>5</sup>Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. <sup>6</sup>Applicant is to place a check mark here if English language Translation is attached.

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Substitute for form 1449A/PTO				Complete if Known		
				Application Number	10/763,885	
INFO	RMATION D	ISC	LOSURE	Filing Date	01/23/2004	
STAT	<b>EMENT BY</b>	APF	PLICANT	First Named Inventor	Xu et al.	
				Group Art Unit	1752	
(use as many sheets as necessary)				Examiner Name	Amanda C. Walke	
Sheet	2	of	17	Attorney Docket Number	P113-55-03	

	T	U.S. Patent D	Ocument	Į.	Date of Publication of	Pages, Columns, Lines,
Examiner Initials*	Cite No.1	Number	Kind Code <sup>2</sup> (if known)	Name of Patentee or Applicant of Cited Document	Cited Document MM-DD-YYYY	Where Relevant Passages or Relevant Figures Appear
	B35	4,826,943		Ito et al.	05-02-1989	
	B36	4,846,931		Gmitter et al.	07-11-1989	
	B37	4,848,911		Uchida et al.	07-18-1989	
	B38	4,857,477		Kanamori	08-15-1989	
	B39	4,883,561		Gmitter et al.	11-28-1989	
	B40	4,891,303		Garza et al.	01-02-1990	
	B41	4,908,298		Hefferon et al.	03-13-1990	
	B42	4,919,748		Bredbenner et al.	04-24-1990	
	B43	4,921,778		Thackeray et al.	05-01-1990	
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	B45	4,931,351		McColgin et al.	06-05-1990	
	B46	4,959,252		Bonnebat et al.	09-25-1990	
	B47	4,964,945		Calhoun	10-23-1990	
	B48	4,976,818		Hashimoto et al.	12-11-1990	
	B49	4,980,316		Huebner	12-25-1990	
	B50	4,999,280		Hiraoka	03-12-1990	
	B51	5,053,318		Gulla et al.	10-01-1991	
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	B53	5,071,694		Uekita et al.	12-10-1991	
	B54	5,072,126		Progler	12-10-1991	
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	B57	5,108,875		Thackeray et al.	04-28-1992	
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Examiner Signature					Date Considered	

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Substitute f	or form 1449A/P	го		Comple	te if Known
				Application Number	10/763,885
INFO	RMATION	DISCL	OSURE	Filing Date	01/23/2004
STAT	<b>EMENT B</b>	Y APPL	<b>ICANT</b>	First Named Inventor	Xu et al.
				Group Art Unit	1752
(u	ise as many shee	ets as necess	ary)	Examiner Name	Amanda C. Walke
Sheet	3	of	17	Attorney Docket Number	P113-55-03

Examiner Cite No. 1 U.S. Patent Document Name of Patentee or Applicant Date of Publication of Where Relevant									
Examiner Initials*	Cite No.'	Number	Kind Code <sup>2</sup> (if known)	Name of Patentee or Applicant of Cited Document	Cited Document MM-DD-YYYY	Where Relevant Passages or Relevant Figures Appear			
	B69	5,212,147		Sheats	05-18-1993				
	B70	5,234,793		Sebald et al.	08-10-1993				
	B71	5,240,550		Boehnke et al.	08-31-1993				
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	B73	5,242,711		DeNatale et al.	09-07-1993	·			
	B74	5,244,818		Jokerst et al.	09-14-1993				
	B75	5,259,926		Kuwabara et al.	09-09-1993				
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	B77	5,277,749		Griffith et al.	01-11-1994				
	B78	5,314,772		Kozicki et al.	05-24-1994				
	B79	5,318,870		Hartney	06-07-1994				
	B80	5,324,683		Fitch et al.	06-28-1994				
	B81	5,328,810		Lowrey et al.	07-12-1994				
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	B87	5,376,810		Hoenk et al.	12-27-1994				
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	B89	5,392,123		Marcus et al.	02-21-1995				
	B90	5,417,802		Obeng	05-23-1995				
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	B97	5,452,090		Progler et al.	09-19-1995				
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	B101	5,480,047		Tanigawa et al.	01-02-1996				
		INTENTIONAL	BLANK						
Examiner					Date				
Signature					Considered				

<sup>\*</sup>EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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Substitute fo	r form 1449A/PTO			Complete if Known		
				Application Number	10/763,885	
INFOR	MATION D	ISCLO	SURE	Filing Date	01/23/2004	
STATE	<b>EMENT BY</b>	<b>APPLI</b>	CANT	First Named Inventor	Xu et al.	
				Group Art Unit	1752	
(use as many sheets as necessary)				Examiner Name	Amanda C. Walke	
Sheet	4	of	17	Attorney Docket Number	P113-55-03	

U.S. Patent Document  Cite No.  U.S. Patent Document  Name of Patentee or Applicant  Date of Publication of  Where Relevant									
Examiner Initials*	Cite No.	Kind Code <sup>2</sup> Number ( <i>if known</i> )	of Cited Document	Cited Document MM-DD-YYYY	Where Relevant Passages or Relevant Figures Appear				
	B102	5,515,167	Ledger et al.	05-07-1996					
	B103	5,523,878	Wallace et al.	06-04-1996					
	B104	5,527,662	Hashimoto et al.	06-18-1996					
	B105	5,545,367	Bae et al.	08-13-1996					
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	B109	5,670,415	Rust	09-23-1997					
	B110	5,700,626	Lee et al.	12-23-1997					
	B111	5,723,176	Keyworth et al.	03-03-1998					
	B112	5,724,145	Kondo et al.	03-03-1998					
	B113	5,725,788	Maracas et al.	03-10-1998					
	B114	5,736,424	Prybyla et al.	04-07-1998					
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	B118	5,760,500	Kondo et al.	06-02-1998					
	B119	5,776,748	Singhvi et al.	07-07-1998					
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	B127	5,907,782	Wu	05-25-1999					
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	B129	5,926,690	Toprac et al.	07-20-1999					
	B130	5,937,758	Maracas et al.	08-17-1999					
	B131	5,942,871	Lee	08-24-1999					
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Examiner Signature				Date Considered					

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	B136	6,035,805		Rust	03-14-2000			
	B137	6,038,280		Rossiger et al.	03-14-2000			
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	B139	6,051,345		Huang	04-18-2000			
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	B150	6,180,239	B1	Whitesides et al.	01-30-2001			
	B151	6,188,150	B1	Spence	02-13-2001			
	B152	6,204,922	B1	Chalmers	03-20-2001			
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	B154	6,245,581	B1	Bonser et al.	06-12-2001			
	B155	6,274,294	B1	Hines	08-14-2001			
	B156	6,326,627	B1	Putvinski et al.	12-04-2001			
	B157	6,329,256	B1	lbok	12-11-2001			
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	B162	6,411,010	B1	Suzuki et al.	06-25-2002			
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	B164	6,455,411	B1	Jiang et al.	09-24-2002			
	B165	6,467,761	B1	Amatucci et al.	10-22-2002			
	B166	6,482,742	B1	Chou	11-19-2002	<del>"</del>		
	B167	6,489,068	B1	Kye	12-03-2002	- T		
	B168	6,495,624	B1	Brown, James F.	12-17-2002			
	B169	6,514,672	B2	Young et al.	02-04-2003			
Examiner			<del> </del>		Date	<del> </del>		
Signature					Considered			

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Sheet 6 of 17

Complete if Known					
Application Number	10/763,885				
Filing Date	01/23/2004				
First Named Inventor	Xu et al.				
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	<del></del>			U.S. PATENT DOCUMENTS	5 	
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	B170	6,534,418	B1	Plat et al.	03-18-2003	
	B171	6,541,360	B1	Plat et al.	04-01-2003	
	B172	6,561,706		Singh et al.	05-13-2003	
	B173	6,565,928	B2	Sakamoto et al.	05-20-2003	
	B174	6,632,742	B2	Yang et al.	10-14-2003	
	B175	6,635,581	B2	Wong	10-21-2003	
	B176	6,646,662	B1	Nebashi et al.	11-11-2003	
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Examiner		-	***************************************		Date	
Signature					Considered	

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17

Substitute for form 1449A/PTO

Sheet

## INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(use as many sheets as necessary)

Complete if Known						
Application Number	10/763,885					
Filing Date	01/23/2004					
First Named Inventor	Xu et al.					
Group Art Unit	1752					
Examiner Name	Amanda C. Walke					
Attorney Docket Number	P113-55-03					

		U.S. Patent Do	cument	I	Date of Publication of	Pages, Columns, Lines.
Examiner Initials*	Cite No.1	Number	Kind Code <sup>2</sup> (if known)	Name of Patentee or Applicant of Cited Document	Cited Document MM-DD-YYYY	Where Relevant Passages or Relevant Figures Appear
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Complete if Known Substitute for form 1449A/PTO **Application Number** 10/763,885 INFORMATION DISCLOSURE Filing Date 01/23/2004 STATEMENT BY APPLICANT **First Named Inventor** Xu et al. 1752 **Group Art Unit** (use as many sheets as necessary) Amanda C. Walke **Examiner Name** 17 Sheet of **Attorney Docket Number** P113-55-03

•	FOREIGN PATENT DOCUMENTS									
Examiner 'Initials*	Cite No. <sup>1</sup>	Office <sup>3</sup>		l Code <sup>5</sup> (nown)	Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T <sup>6</sup>		
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Substitu	te for form 1449E	B/PTO		Complete if Known		
:				Application Number	10/763,885	
INFO	DRMATIO	N DISC	LOSURE	Filing Date	01/23/20904 Xu et al.	
STA	TEMENT	BY API	PLICANT	First Named Inventor		
				Group Art Unit	1752	
	(use as many sh	neets as nec	essary)	Examiner Name	Amanda C. Walke	
Sheet	9	of	17	Attorney Docket Number	P113-55-03	

	OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS								
	Examiner Initials*	Cite No.1	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T <sup>2</sup>					
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Examiner	·	Date	
Signature		Considered	

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Substitu	ute for form 1449B/P1	ГО		Complete if Known		
				Application Number	10/763,885	
INF	ORMATION	DIS	CLOSURE	Filing Date	01/23/2004	
STA	TEMENT B'	Y AF	PPLICANT	First Named Inventor	Xu et al.	
				Group Art Unit	1752	
	(use as many sheet	ts as n	ecessary)	Examiner Name	Amanda C. Walke	
Sheet	10	of	17	Attorney Docket Number	P113-55-03	

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Signature	Considered	

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Substit	ute for form 1449B	/PTO		Complete if Known		
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INF	ORMATION	N DISC	LOSURE	Filing Date	01/23/2004	
STA	ATEMENT I	BY APF	PLICANT	First Named Inventor	Xu et al.	
				Group Art Unit	1752	
	(use as many sh	eets as nece	essary)	Examiner Name	Amanda C. Walke	
Sheet	11	of	17	Attorney Docket Number	P113-55-03	

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Examiner	·	Date		
Signature		Consider	ered	

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Substitu	ute for form 1449B/	РТО		Complete if Known		
				Application Number	10/763,885	
INF	ORMATION	DISC	LOSURE	Filing Date	01/23/2004	
STATEMENT BY APPLICANT				First Named Inventor	Xu et al.	
				Group Art Unit	1752	
(use as many sheets as necessary)				Examiner Name	Amanda C. Walke	
Sheet	12	of	17	Attorney Docket Number	P113-55-03	

OTHER PRIOR	R ART - N	NON PATENT LITERATURE DOCUMENTS	
Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T <sup>2</sup>
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Signature	Considered	

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INF	ORMATION	DISC	CLOSURE	Filing Date	01/23/2004	
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				Group Art Unit	1752	
(use as many sheets as necessary)			ecessary)	Examiner Name	Amanda C. Walke	
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				Group Art Unit	1752	
(use as many sheets as necessary)			essary)	Examiner Name	Amanda C. Walke	
Sheet	14	of	17	Attorney Docket Number	P113-55-03	

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Substitu	ute for form 1449B/F	то	-	Complete if Known	
				Application Number	10/763,885
INF	ORMATION	DISC	LOSURE	Filing Date	01/23/2004
STA	TEMENT B	Y AP	PLICANT	First Named Inventor	Xu et al.
				Group Art Unit	1752
(use as many sheets as necessary)				Examiner Name	Amanda C. Walke
Sheet	15	of	17	Attorney Docket Number	P113-55-03

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Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	
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				Application Number	10/763,885	
INFORMATION DISCLOSURE			CLOSURE	Filing Date	01/23/2004	
STATEMENT BY APPLICANT		First Named Inventor	Xu et al.			
				Group Art Unit	1752	
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Sheet	16	of	17	Attorney Docket Number	P113-55-03	

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**Examiner Name** 

Attorney Docket Number

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